



Seiko Seiki STP-H200C, H2000C

Technical Specifications

| ITEM | MODEL | STP-H200C | STPH-300C | STP-H600C | STP-H1000C | STP-H2000C | |
|--------------------------------------|--|---|---------------------------------|----------------------------|----------------------------------|------------------------------|------------------------------------|
| Nominal diameter | Inlet ^{Note 1)} | ICF152 | ICF203 | | ICF253 | ICF305 | |
| | Outlet | DN25KF | | KF40 | | | |
| Pumping speed | for N ₂ l/s | 220 | 320 | 600 | 1000 | 2000 | |
| | for He l/s | 180 | 290 | 550 | 900 | 1800 | |
| | for H ₂ l/s | 160 | 250 | 500 | 800 | 1600 | |
| Compression ratio | for N ₂ | >10 ⁸ | | | | | |
| | for He | 3 x 10 ⁴ | | 10 ⁵ | | 10 ⁴ | |
| | for H ₂ | 2 x 10 ³ | | 10 ⁴ | | 10 ³ | |
| Ultimate pressure ^{Note 2)} | Pa (Torr) | 10 ⁻⁷ (10 ⁻⁹) After baking out | | | | | |
| Admissible Inlet Pressure | Pa (Torr) | 400 (3) [Water cooling], 133 (1) [air cooling], 6.65 (0.05) [spontaneous cooling] | | | *67(0.5), *53(0.04) ☆0.93(0.007) | | ※13.3(0.1), *1.3(0.01) ☆0.1(0.001) |
| Admissible Outlet Pressure | Pa (Torr) | 665 (5) [water cooling], 400 (3) [air cooling], 13 (0.1) [spontaneous cooling] | | | *399(3), *266(2), ☆266(2) | | ※266(2) *266(2) ☆133(1) |
| Throughput | | 1400 SCCM, 400 Pa (3 Torr) | | 650 SCCM, 67 Pa (0.5 Torr) | | 600 SCCM, 13.3 Pa (0.1 Torr) | |
| Rotational speed | r.p.m. | 36,000 | | 35,000 | | 27,000 | |
| Start-up time | min. | 5 | | | 7 | | |
| Stopping time | min. | 5 | | | 7 | | |
| Vibration (measured) | μm (O-P) | < 0.01 (at 36,000 r.p.m) | | < 0.01 (at 35,000 r.p.m) | | < 0.01 (at 27,000 r.p.m) | |
| Bake-out temperature | °C | < 120 | | | | | |
| Lubricant | | Not required | | | | | |
| Mounting position | | Free | | | | | |
| Type of cooling | | Spontaneous cooling, Air cooling, Water cooling | | | | | |
| Recommended backing pump | l/min | 240 | | | 540 | | |
| Weight | Pump kg | 20 | | 30 | 31 | 63 | |
| | Controller kg | 21 | | 40 | | | |
| Control unit | Power supply | ACV | 200 ~ 240 ±10%/100~120 ±10% | | 200 ~ 240 ±10% | | |
| | Frequency | Hz | 50/60 ±2 | | | | |
| | Phase | | Single phase | | | | |
| | Motor drive | | Transistor three phase inverter | | | | |
| | Output voltage (Continuous operating) | ACV | 54 | | 82 | 85 | |
| | Rated frequency (Continuous operating) | Hz | 600 | | 583 | 450 | |
| | Admissible ambient temperature (Storage temperature) | °C | 0 ~ 40 (-20 ~ 40) | | | | |
| | Battery | | 12V, 1.8 Ah x 2 | | 12V, 1.8 Ah x 4 | | |
| | Input power | at start (VA) | 1200 | | 2600 | | |
| | | at running (VA) | 300 ~ 1000 | | 1000 | | |

Note 1) ISO, ASA or VG is available. Note 2) Theoretical pressure is 10⁻⁹ Pa (10⁻¹¹ Torr)

※=Water cooling * =air cooling
☆=spontaneous cooling



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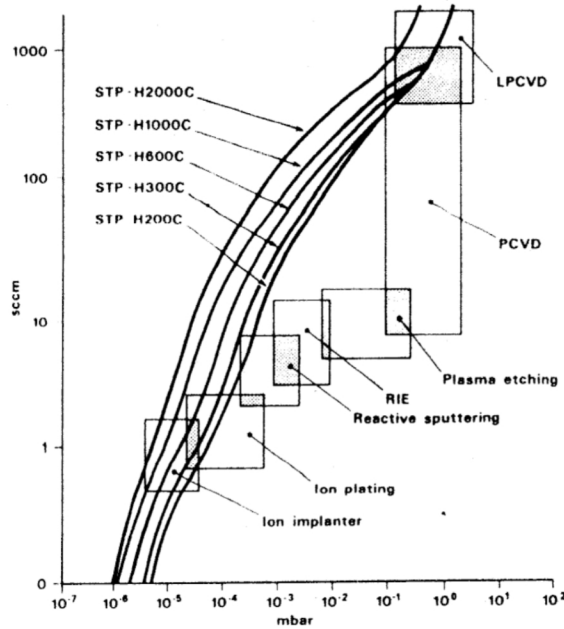
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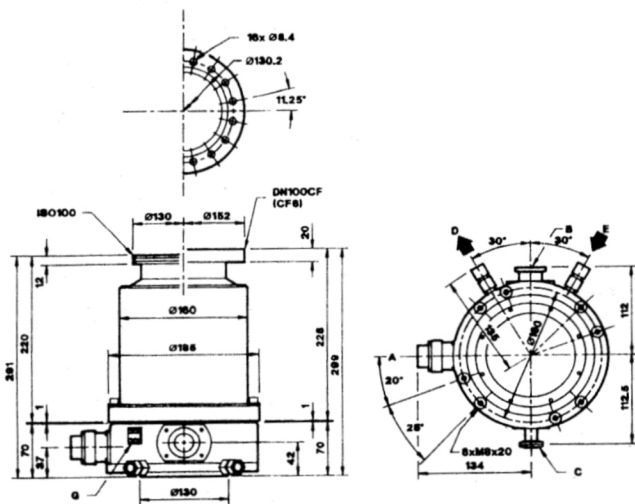
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Seiko Seiki STP-H200C, H2000C Pumping Curves

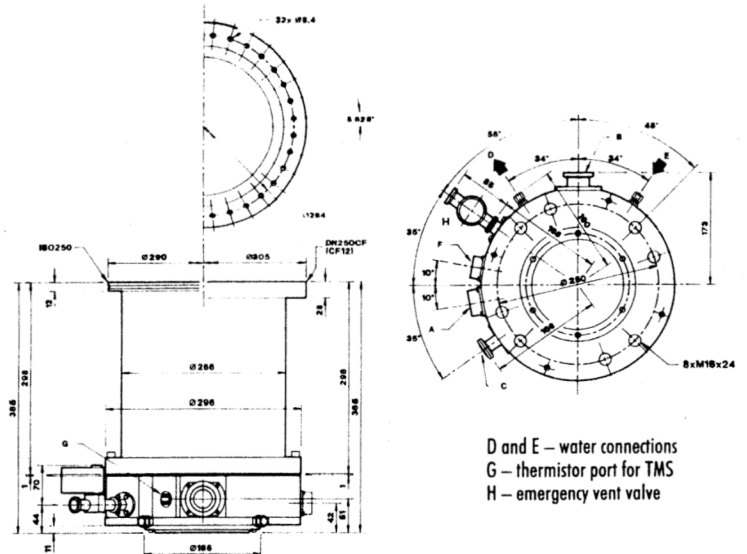


Dimensions

STP-H200C



STP-H2000C





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Seiko Seiki STP-H200C, H2000C Features & Benefits

- high throughput, corrosion resistant series
- high reliability, maintenance free
- high pressure pumping
- molecular drag stage
- automatic balancing system
- compact design, small footprint
- advanced rotor technology
- installation in any orientation
- oil free
- low vibration



Applications

- plasma & ECR etch • film deposition • sputtering • ion implantation source • beam line pumping • MBE • diffusion • photo resist stripping
- crystal / epitaxial growth • wafer inspection • load lock chambers

